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IFUAP

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Apr. 2, 2008

To: Compissioner for Patents

O. Box 1450

Alexandria, VA 22313-1450

Fr:

Stephen B. Ackerman, Reg. No. 37,761

28 Davis Avenue

Poughkeepsie, N.Y. 12603

Subject:

Serial No.

10/786,807

02/25/2004

H. M. CHEN

"METHOD FOR IMPROVING SEMICONDUCTOR WAFER TEST ACCURACY"

Grp. Art Unit: 2822

AU, BACH

## RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

In response to the Non-Final Office Action mailed Oct. 5, 2007, please amend the aboveidentified application for patent and consider the remarks, as follows:

## CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on Apr. 7, 2008.

Stephen B. Ackerman, Reg. No. 37,761

Signature \_

Date April 7,201